

ECM-100
Divisional Report
September 22, 2006
Plasma Science and Technique Divisional Committee

Submitted by David Ruzic

Over the last 6 months several email exchanges have taken place with regards to division business. The most noteworthy is work on the IVC-17 program. There has also been an effort to collect material for the Highlights seminar.

A meeting of the Plasma Science and Technique Divisional Committee was held in Seoul Korea at the ECM-100 meeting on Thursday September 21st 2006. The following items were discussed:

1. Results from Dr. Alan Webb's IUVSTA sponsored and funded workshop on Plasma measurement techniques for process control that was held earlier in September 2006. This meeting was a success both from a technical point-of-view and broke even financially. IUVSTA's support is gratefully acknowledged.
2. The Programme for the IVC-17 (Stockholm Sweden in 2007) Plasma Science Division. Dr. Ulf Karlsson, the over-all chair of the conference was present for the discussions. The committee has started preparing session ideas and lists of invited speakers. Those will be moulded into the outlines of a complete program.